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Form PTO-1449 (modified)

List of Patents and Publications
For Applicant's Information
Disclosure Statement
(Use several sheets if necessary)

ATTY. DOCKET NO: 5298-02501

APPLICANT: Sethuraman et al.

FILING DATE: Herewith

SERIAL NO: Unknown

GROUP: Unknown

2823

JES74 U.S. PTO

09/7791231

02/07/01

U.S. PATENT DOCUMENTS

EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
Lee		3,629,023	12/21/71	Strehlow			
		3,979,239	9/7/76	Walsh			
		4,256,535	3/17/81	Banks			
		4,261,791	4/14/81	Shwartzman			
		4,373,991	2/15/83	Banks			
		4,505,720	3/19/85	Gabor et al.			
		4,600,469	7/15/86	Fusco et al.			
		4,677,043	6/30/87	Cordes, III et al.			
		4,768,883	9/6/88	Waldo et al.			
		4,778,532	10/18/88	McConnell et al.			
		4,789,648	12/6/88	Chow et al.			
		4,879,258	11/7/89	Fisher			
		4,933,715	6/12/90	Yamada et al.			
		4,944,836	7/31/90	Beyer et al.			
		4,954,141	9/4/90	Takiyama et al.			
		4,956,313	9/1990	Cote et al.			
		4,962,423	10/9/90	Yamada et al.			
		4,968,381	11/6/90	Prigge et al.			
		4,986,878	1/22/91	Malazgirt et al.			
		5,032,203	7/16/91	Doy et al.			
		5,057,462	10/15/91	Eisenberg et al.			
		5,064,683	11/12/91	Poon et al.			
		5,084,419	1/28/92	Sakao			
		5,209,816	5/11/93	Yu et al.			
		5,262,354	11/1993	Cote et al.			
Lee		5,273,558	12/28/93	Nelson et al.			

EXAMINER:

Brian Ming Lee

DATE CONSIDERED:

6/27/02

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the patent owner.

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U.S. PATENT DOCUMENTS

EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
<i>Lee</i>		5,288,333	2/22/94	Tanaka et al.			
		5,312,777	5/1994	Cronin et al.			
		5,320,706	6/14/94	Blackwell			
		5,320,978	6/14/94	Hsu			
		5,340,370	8/23/94	Cadien et al.			
		5,346,584	9/13/94	Nasr et al.			
		5,362,668	11/8/94	Tasaka			
		5,362,669	11/8/94	Boyd et al.			
		5,363,550	11/15/94	Aitken et al.			
		5,376,482	12/27/94	Hwang et al.			
		5,389,194	2/14/95	Rostoker et al.			
		5,389,579	2/14/95	Wells			
		5,392,361	2/21/95	Imaizumi et al.			
		5,395,801	3/7/95	Doan et al.			
		5,397,741	3/1995	O'Connor et al.			
		5,401,691	3/28/95	Caldwell			
		5,406,111	4/11/95	Sun			
		5,435,772	7/25/95	Yu			
		5,436,488	7/25/95	Poon et al.			
		5,441,094	8/15/95	Pasch			
		5,453,639	9/1995	Cronin et al.			
		5,459,096	10/17/95	Venkatesan et al.			
		5,468,983	11/21/95	Hirase et al.			
		5,486,265	1/23/96	Salugsugan			
		5,492,858	2/20/96	Bose et al.			
		5,494,857	2/27/96	Cooperman et al.			
<i>Lee</i>		5,503,962	4/2/96	Caldwell			

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<i>Lee</i>		5,525,840	6/11/96	Tominaga			
		5,531,861	7/2/96	Yu et al.			
		5,541,427	7/30/96	Chappell et al.			
		5,551,986	9/3/96	Jain			
		5,573,633	11/12/96	Gambino et al.			
		5,578,523	11/26/96	Fiordalice et al.			
		5,591,239	1/7/97	Larson et al.			
		5,595,937	1/21/97	Mikagi			
		5,607,345	3/4/97	Barry et al.			
		5,616,513	4/1/97	Shepard			
		5,629,242	5/13/97	Nagashima et al.			
		5,643,406	7/1/97	Shimomura et al.			
		5,643,823	7/1/97	Ho et al.			
		5,643,836	7/1/97	Meister et al.			
		5,652,176	7/29/97	Maniar et al.			
		5,656,097	8/12/97	Olesen et al.			
		5,664,990	9/9/97	Adams et al.			
		5,665,202	9/9/97	Subramanian et al.			
		5,666,985	9/16/97	Smith, Jr. et al.			
		5,676,587	10/1997	Landers et al.			
		5,702,977	12/30/97	Jang et al.			
		5,721,172	8/1999	Jang et al.			
		5,728,308	3/17/98	Muroyama			
		5,776,808	7/7/98	Muller et al.			
		5,837,612	11/17/98	Ajuria et al.			
<i>Lee</i>		5,906,532	5/25/99	Nakajima et al.			

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Kevin Mery Lee

DATE CONSIDERED:

6/27/02

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U.S. PATENT DOCUMENTS

EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
Lee		5,919,082	7/6/99	Walker et al.			
Lee		5,928,959	7/1999	Huckels et al.			
Lee		5,943,590	8/1999	Wang et al.			
Lee		5,952,687	9/14/99	Kawakubo et al.			

FOREIGN PATENT DOCUMENTS

EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION. YES/NO
Lee		0 303 061	2/15/89	Europe			

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

not consider		Singer, "CMP Developers Take Aim at STI Applications" and "Slurry-Free CMP Reduces Dishing, Speeds Process," <u>Semiconductor International</u> , Volume 21, No. 2, p. 40.
to provide the documents		Ali et al., "Chemical-Mechanical Polishing of Interlayer Dielectric: A Review," <u>Solid State Technology</u> , October 1994, pp. 63-68.
		Sivaram et al., "Developments in Consumables Used in the Chemical Mechanical Polishing of Dielectrics," <u>International Conference on Solid State Devices & Materials</u> , August 1995, p. 166
		Wolf, <u>Silicon Processing for the VLSI Era Volume 2: Process Integration</u> , Lattice Press 1990, pp. 189-191.

EXAMINER: Kevin Mary Lee DATE CONSIDERED: 6/27/02

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